Why not

- **Plasma Control** (Optical Emission Spectroscopy)
- **Etch rate measurement** (Interferometry)

**in a single Endpoint Instrument?**

**LEM camera**
- Local measurement on sample
- Laser spot # 50 µm
- VIS 670 nm or IR 905 nm

**EV-140**
- Global Plasma Monitoring
- High grade spectrometer
- [200, 800] nm

**Only 1 PC controller (Win7)**
- Both sensors simultaneously
- 1 real-time software
- Engineering add-ons

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